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- A method for forming a hybrid active electronic and optical circuit using a
- lithography mask, the hybrid active electronic and optical circuit comprising an active electronic device and at least one optical device on a Silicon-On-Insulator (SOI) wafer, the
- SOI wafer including an insulator layer and an upper silicon layer, the upper silicon layer
- including at least one component of the active electronic device and at least one component
- of the optical device, the method comprising projecting the lithography mask onto the SOI
- waver in order to simultaneously pattern the component of the active electronic device and
- the component of the optical device on the SOI wafer.
- 2. The method of claim 1, wherein altering an electric voltage level applied to the
 - active electronic device effects the free carrier distribution in a region of the optical device,
 - and thereby changes the effective mode index of the region of the optical device.
 - The method of claim 1, wherein the optical device is an active optical device. 3.
 - 4. The method of claim 1, wherein the optical device is a passive optical device.
 - 5. The method of claim 1, wherein the optical device is a focusing mirror.
 - The method of claim 1, wherein the optical device is an input/output coupler that 6. couples light into a waveguide.
 - 7. The method of claim 1, wherein the optical device is a Fabry-Perot cavity.

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- 8. The method of claim 1, wherein the optical device is a wavelength division multiplexer modulator.
- 9. The method of claim 1, wherein the optical device is an evanescent coupler.
- 10. The method of claim 1, wherein the optical device is a diode.
- 11. The method of claim 1, wherein the optical device is a transistor.